

February 13, 2020

EXTENSION OF AWARD POSTING DATE

THE DATE FOR POSTING THIS AWARD HAS BEEN EXTENDED TO FEBRUARY 19, 2020 PENDING FURTHER EVALUATION.

REFERENCED RFP NUMBER:

USC-IFB-3584-AS

FOR:

Furnish, Deliver, and Install Reactive Ion Etching Machine and Plasma Cleaner Cleaning System Equipment

ISSUE DATE:

January 6, 2020

DEADLINE FOR RESPONSES:

February 6, 2020

Hunnedy Ahell

Ashley Kennedy-Shell Buyer